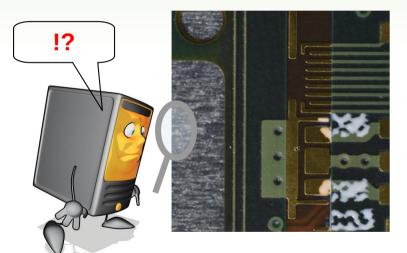
Improving the Visual Inspection of new detector components with Anomaly Detection algorithms



Presenter : Louis VASLIN





Quality Control

• New Detectors for New Physics

<u>Good detector quality</u> is required to reach our goal => Quality Control (QC) during detector production Need <u>bigger</u> and <u>more complex</u> detectors

- Visual Inspection of detector components Look for visible defects on detector components
 - => Prevent future failures
 - => Improve fabrication process

Time consuming and error prone process

ITk pixel modules

• New Inner Tracker (ITk) for ATLAS detector

Part of the <u>High Luminosity upgrade</u> of **ATLAS experiment** 8372 Pixel modules

Pixel End Caps

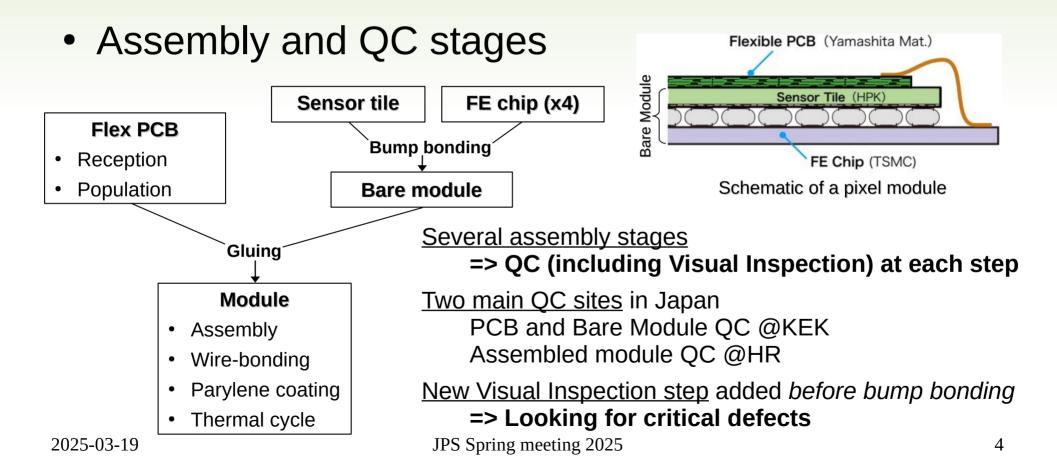
Pixel module production in Japan Pixel End Caps
<u>2800 pixel modules</u> to be assembled and delivered

=> Main production as already started

Major challenge for QC

=> New tools are needed to improve QC procedures

ITk pixel modules



AI for Visual Inspection

• Objective

Improve the <u>efficiency</u> and <u>reliability</u> of Visual Inspection => Use deep Learning techniques

• Two categories of defects

AI for Visual Inspection

Objective

Improve the <u>efficiency</u> and <u>reliability</u> of Visual Inspection => Use deep Learning techniques

• Two categories of defects Statistical anomalies

Anomalies that appear in a <u>minority of images</u> => O(1%) occurrence rate

Very <u>few examples</u> available

=> Cannot make labeled dataset

Unsupervised defect detection

AI for Visual Inspection

Objective

Improve the <u>efficiency</u> and <u>reliability</u> of Visual Inspection => Use deep Learning techniques

• Two categories of defects Statistical anomalies

Anomalies that appear in a <u>minority of images</u> => O(1%) occurrence rate

Very <u>few examples</u> available

=> Cannot make labeled dataset

Unsupervised defect detection

Expert anomalies

More <u>recurrent/common anomalies</u> => Recognized as defects by experts

Many examples available

=> Can make labeled dataset

Supervised defect classification

Unsupervised defect detection

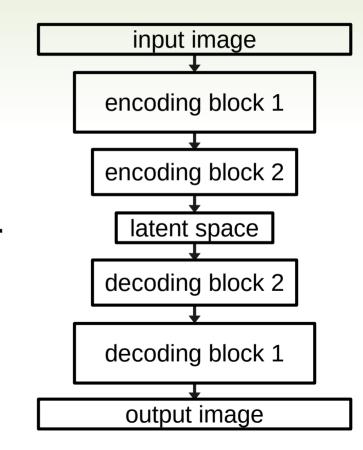
• Denoising Auto-Encoder

<u>Reconstruct main input fetures</u> and <u>remove defect-like pattern</u>

=> Enhance sensitivity for defect detection Select <u>pixel areas</u> with **high reco error**

Clustering and filtering
Apply clustering to selected pixels
Keep only major clusters

=> Defect candidates



Unsupervised defect detection

• Custom noise patterns

Add noise patterns on input images during training

=> Randomize size, rotation and color

Pattern examples

Compute **MSE loss** between <u>output</u> and <u>original input</u> <u>Noise patterns</u> are made "by hand" to *ressemble* defect => Expert knowlege

• Selection threshold

Use *clean* test images and <u>compute recontruction error</u>

=> Define threshold based on image without major defects

Supervised defect classification

 Feature Pyramid Network Input image Extract high level features from block 1 input image upsample Successive dimension reduction block 2 **Defect list** upsample => Pattern of different sizes block 3 Classification head network upsample block 4 Use FPN feature space to <u>classify</u> specific defects **FPN** Classification => Multiple classification objective head 2025-03-19 10 JPS Spring meeting 2025

Supervised defect classification

• FPN pretraining

<u>Generic feature extraction</u> with *Auto-Encoder-like* objective Training with images of <u>various components and stages</u> => Common training of each specific components

• Main classifier training

Use the **same pretrained FPN** for <u>each component</u>

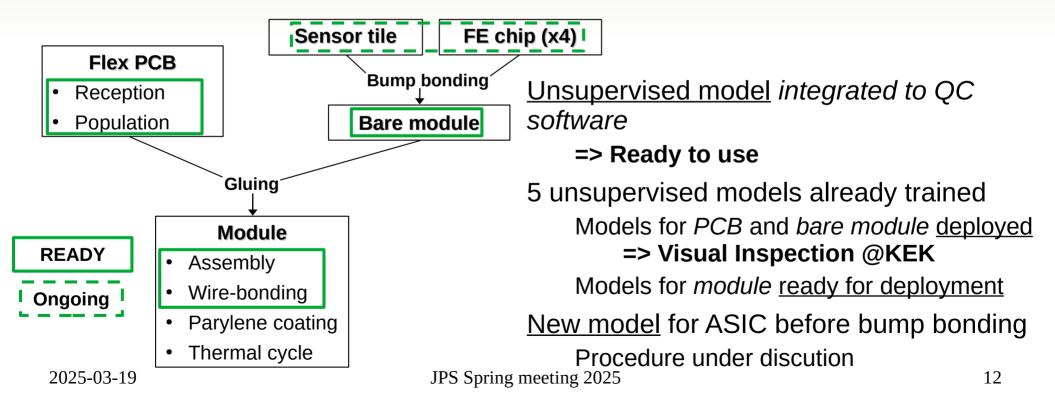
Use one <u>binary cross-entropy</u> term per **target defect class**

 $\log(x, y) = \sum_{C} y_{C} \log(x_{C}) + (1 - y_{C}) \log(1 - x_{C}) \quad \leftarrow \text{ one score per category}$

Improved training loop under testing JPS Spring meeting 2025

Deployment status

• Available models



Data preparation

• Data Acquisition

<u>Camera and microscope</u> with moving stage

• Data augmentation

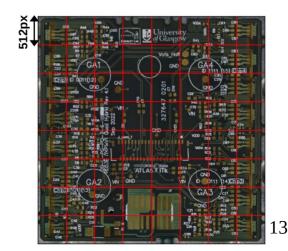
Duplicate source images with random modifications

=> Cropping, scaling, brightness

Split augmented images in 8x8 tiles (512x512 each)



Image acquisition system @KEK



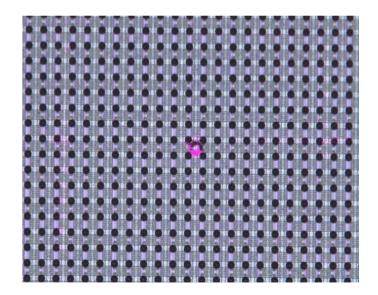
Some results

Unsupervised defect detection

Visual Inspection before Bare Module assembly

=> Latest model

Investigating <u>critical defects</u> => Might cause failure in later stages Selected area is colored in pink => Successful defect detection Still need to *reduce fake rates*

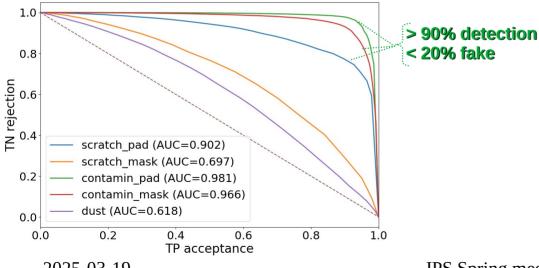


Some results

Supervised defect classification

ROC curves showing performances for <u>5 defect categories</u>

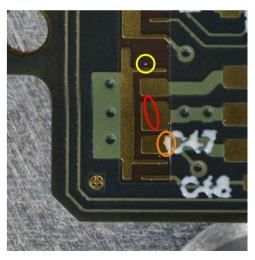
Good performances for 3 out of 5



Application to a flex PCB image

3 defect categories detected Dust, contamination and scratch

All 3 defects were properly identified



Conclusion

• Improving QC for ITk pixel modules

Use <u>Deep Learning techniques</u> to improve <u>Visual Inspection</u> => Find more defect faster

Successful integration of unsupervised model => Part of ITk QC software

Generic API for AI-based Visual Inspection

Available on GitHub and PyPI

=> Facilitate integration into existing QC framework

Documentation and development features will be implemented

Thank you !

ありがとうございます!